AMENDMENTS TO THE SPECIFICATION

Please replace the Paragraph at Page 1, line 6 with the following paragraph rewritten in amendment format:

The present invention relates to a device manufacturing apparatus and a device manufacturing method provided with a discharge head capable of discharging a ~~liquid~~droplet.

Please replace the Paragraph at Page 2, line 19 with the following paragraph rewritten in amendment format:

A first aspect of the present invention is a device manufacturing apparatus has a discharge head for discharging a ~~liquid~~droplet containing a functional material, a stage for supporting a substrate on which the ~~liquid~~droplet is discharged, and which is capable of moving relative to the discharge head, a carrier for carrying the substrate, a detector for detecting a discharge condition of the ~~liquid~~droplet which is discharged from a discharge nozzle formed in the discharge head, and a controller for executing a detection operation by the discharge device during a carrying operation of the substrate.

Please replace the Paragraph at Page 3, line 1 with the following paragraph rewritten in amendment format:

Furthermore, a second aspect of the present invention is a device manufacturing method has a step of discharging a ~~liquid~~droplet containing a functional material onto a substrate by means of a discharge nozzle in a discharge head, a carrying step of carrying the substrate, and a detection step of detecting a discharge condition of the ~~liquid~~droplet

which is discharged from the discharge nozzle, during a carrying operation of the substrate.

Please replace the Paragraph at Page 3, line 14 with the following paragraph rewritten in amendment format:

Consequently, the non-performing nozzle detection operation can be carried out without interfering with the discharge operation which discharges the ~~liquid~~droplet onto the substrate in order to manufacture the device. Therefore a device having a desirable performance without missing dots can be manufactured without a decrease in throughput. Furthermore, during the loading and unloading operation of the substrate, the time out of that for the overall device manufacturing process, for discharging the ~~liquid~~droplet from the discharge nozzle is comparatively long. Therefore performing the non-performing nozzle detection operation during this loading and unloading operation is effective from the viewpoint of improving throughput, and from the viewpoint of preventing clogging of the discharge nozzles.

Please replace the Paragraph at Page 3, line 23 with the following paragraph rewritten in amendment format:

Furthermore, preferably the detector has a light emitter for emitting a detection light, and a receiver for receiving the detection light emitted from the light emitter, and the receiver determines whether the ~~liquid~~droplet is being discharged from the discharge nozzle, based on changes in the intensity of the detection light received by the receiver due to the ~~liquid~~droplet passing through the optical path of the detection light.

Please replace the Paragraph at Page 5, line 15 with the following paragraph rewritten in amendment format:

The second aspect preferably has the steps of emitting detection light towards a receiver, and determining whether the ~~liquid~~droplet is being discharged from the discharge nozzle, based on changes in the intensity of the detection light received by the receiver due to the ~~liquid~~droplet passing through the optical path of the detection light.

Please replace the Paragraph at Page 14, line 9 with the following paragraph rewritten in amendment format:

The control unit CONT executes a non-performing nozzle detection step (detection step) for detecting whether or not liquid (a droplet) is being discharged from the discharge nozzle 11 of the discharge head 1, while the operation of carrying the substrate P (carrying step) to or from the stage unit 2 is being performed by the carrier 3. The control unit CONT after instructing the start of the loading and unloading operation for the carrier 3 in step S4, starts non-performing nozzle detection operation by the detection apparatus 30. At first, when the non-performing nozzle detection operation is being carried out, the control unit CONT performs a calibration of the detector 32 (step S5).

Please amend the Abstract section of the specification as rewritten in amendment format.

A device manufacturing apparatus includes a discharge head discharging a ~~liquid~~droplet containing a functional material, a stage supporting a substrate on which the ~~liquid~~droplet is discharged, and which is capable of moving relative to the discharge head,

a carrier carrying the substrate, a detector detecting a discharge condition of the ~~liquid~~droplet which is discharged from a discharge nozzle formed in the discharge head, and a controller executing a detection operation by the discharge device during a carrying operation of the substrate.